

## ABSTRACT

METHOD FOR MONITORING AND / OR CONTROLLING THE  
STATUS OF A PLASMA IN A PLASMA SPECTROMETER AND  
SPECTROMETER FOR IMPLEMENTING SUCH A METHOD

## APPLICANT

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## INVENTION

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A method for monitoring and/or controlling the positioning and/or condition of a plasma in a plasma spectrometer, which comprises :

- acquiring image data of the plasma through a video-camera (7), and
- a) displaying on a display device (10) a plasma image from the acquired image data ; and/or
- b) storing the image data in a computer unit (9).

Application to inductively coupled high frequency plasma optical emission and mass spectrometers.

Figure 1